



648.43545X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: M. YAKUSHIJI, et al.  
Serial No: 10/787,461  
Filed: FEBRUARY 27, 2004  
Title: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD  
Group AU: 1763  
Examiner: Luz L. Alejandro Mulero  
Confirm. No: 7834

AMENDMENT

**Mail Stop: AMEND - FEE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 30, 2006

Sir:

In response to the Office Action mailed November 30, 2005, the period for response having been extended for one (1) month by the attached Petition for Extension of Time, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.